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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

: GROUP ART UNIT: 1754

: EXAMINER: Timothy VANOY

IN RE APPLICATION OF

Hiroshi IKEDA et al

SERIAL NO.: 09/463,961

FILED: May 25, 2000

FOR: PROCESS AND APPARATUS FOR TREATING

SEMICONDUCTOR PRODUCTION EXHAUST GASES

AMENDMENT AND REQUEST FOR RECONSIDERATION UNDER 37 C.F.R. §1.116

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Official Action of May 5, 2003, Applicants respectfully request reconsideration of the above-identified application in view of the following amendments and remarks.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 4 of this paper.

10/8/3